

Near Field Pattern $\lambda=470\text{ nm}$

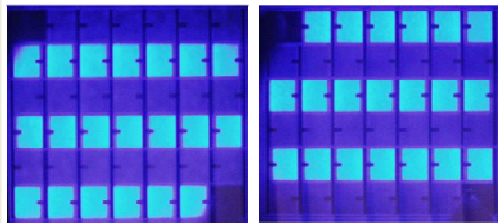
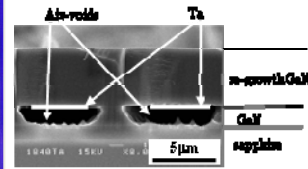


Fig.1



The cross-sectional SEM image of GaN on Ta-GaN/sapphire.

Fig.2

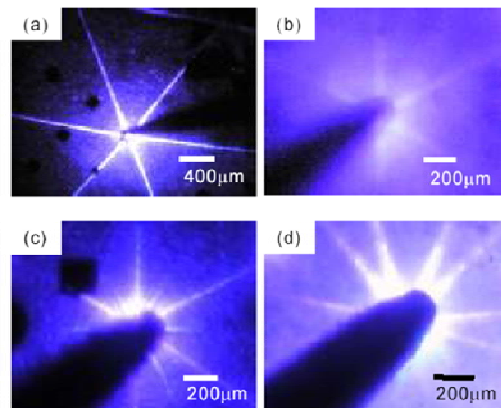
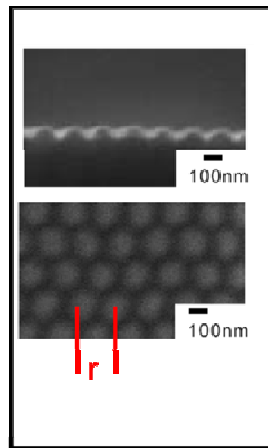


Fig.3

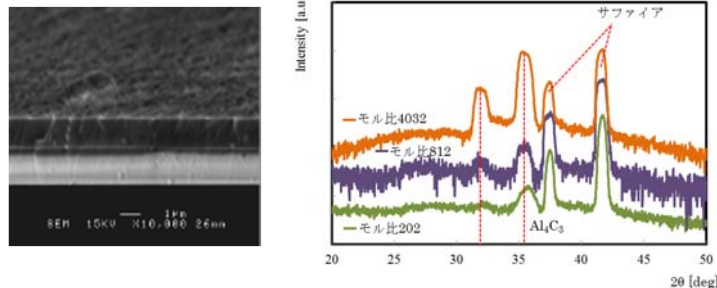


Fig.4

InGaAlN and AIC LEDs are researched.

A high voltage LED is developed. (Fig.1)

Ta-GaN is etched to sapphire during growth, and GaN, the epitaxial layer, is peeled off on Si, for example. (Fig.2)

Nano-pattern is formed on GaN, and their far field pattern are viewed as shown in Fig.3 (a) $r=200\text{ nm}$, (b) $r=300\text{ nm}$, (c) $r=400\text{ nm}$ and (d) $r=500\text{ nm}$. It is clear that the 6th fold pattern is clearly visible for 200 nm which is 6 times for the emitting light.

P-type Mg-Ga $_{1-x}$ Al $_x$ N for $x>0.3$ is affected by the too deep level of Mg from the valence band, and it becomes an insulator, while C-doped AlGa $_x$ N is possible candidate for p-type conduction. We are making an effort to make carbon-doped AlGa $_x$ N or AlN a p-type conduction.

We are growing AIC on sapphire, SiC and Si. SEM and X-ray rocking curve are shown in Fig.4, where a substrate is sapphire.

Keywords: MOCVD, LED, AlGaInN, AIC

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